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(71) Applicant (for all designated States except US): **HAL-LIBURTON ENERGY SERVICES, INC.** [US/US]; 10200 Bellaire Boulevard, Houston, Texas 77072 (US).

(72) Inventors; and

(75) Inventors/Applicants (for US only): **DYKSTRA, Jason D.** [US/US]; 3405 Hillpark Lane, Carrollton, Texas 75007 (US). **FRIPP, Michael Linley** [US/US]; 3826 Cemetery Hill Rd., Carrollton, Texas 75007 (US).

(74) Agents: **PRATT, John S.** et al.; Kilpatrick Townsend & Stockton LLP, 1100 Peachtree Street, Suite 2800, Atlanta, Georgia 30309 (US).

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(54) Title: FLOW-AFFECTING DEVICE

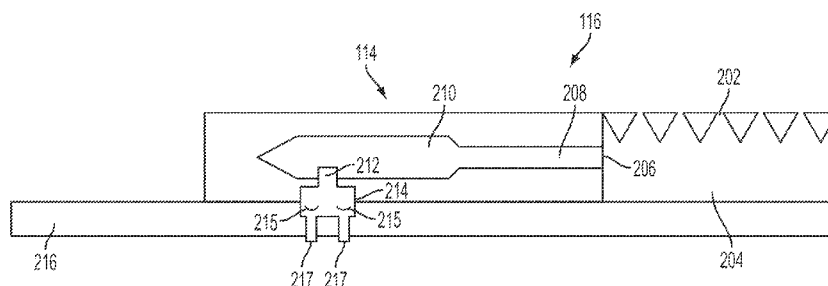


FIG. 2

(57) Abstract: Fluid flow influencer devices in chambers subsequent to vortex assemblies are described. A flow-affecting device can move from a first position to a second position based on a flow path of fluid flowing from the vortex assembly to the chamber. The flow path may depend on an amount of rotation of the fluid from the vortex assembly. The flow-affecting device in the first position can substantially allow fluid to flow through a chamber exit opening. The flow-affecting device in the second position can substantially restrict fluid from flowing through the chamber exit opening.

